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**Position** Professor  
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Degree	<ul style="list-style-type: none"> <li>• 1983 Kon-Kuk University (B.S.E.E.)</li> <li>• 1985 University of Notre Dame (M.S.E.E.)</li> <li>• 1990 South Dakota School of Mines and Technology (Ph. D.)</li> </ul>
Experience	<ul style="list-style-type: none"> <li>• 1992~Present Incheon National University Professor, Assistant, Associate and Professor</li> <li>• 2010~2012 Dean of International Affairs, Incheon National University</li> <li>• 2002~2003 Visiting Scholar, Auburn University</li> <li>• 1990~1992 Senior Researcher, Samsung Semiconductor Research CTR.</li> <li>• 1985~1986 Researcher, Hyundai Mabukri Research CTR</li> </ul>
M a j o r	<ul style="list-style-type: none"> <li>• Electronic Materials(semiconductor, thin film process and device), Plasma Process</li> </ul>
Teaching	<ul style="list-style-type: none"> <li>• Semiconductor Physics, Integrated Circuit Process, Semiconductor Device Physics, Thin Film Engineering, Vacuum Engineering, Electron Microscope</li> </ul>
Representative Research	<ul style="list-style-type: none"> <li>• “Comparative Modelling of NOx and SO2 Removal from Pollutant Gases using Pulsed-Corona and Silent Discharges”, Journal of Physics D: Applied Physics, Vol. 33, No. 14, July 21, 2000, pp.1716-1727</li> <li>• “Analysis of High Vacuum System Based on the Application of Vacuum Materials”, Hyung-Taek Kim, Transactions on Electrical and Electronic Materials, Vol. 14 No 6, 334-338, 2013</li> </ul>
Researches	<ul style="list-style-type: none"> <li>• “Simulation of Modeling Characteristics of Pumping Design Factor on Vacuum System”, Hyung-Taek Kim, Han-Ho Cho, International Journal of Advanced Smart Convergence Vol.5 No 2, 01-07, 2016</li> <li>• “Simulation of Effects of Variable Conductance Throttle Valve on the Characteristics of High Vacuum System”, Hyung-Taek Kim, Han-Ho Cho, International Journal of Internet, Broadcasting and Communication, Vol. 7 No 2, 28-35, 2015</li> <li>• “Analysis of High Vacuum System Based on the Application of Vacuum Materials”, Hyung-Taek Kim, Transactions on Electrical and Electronic Materials, Vol. 14 No 6, 334-338, 2013</li> <li>• “Simulation of Vacuum Characteristics by Applications of Vacuum Valve in Display Processing”, Hyung-Taek Kim, Journal of the Institute of Webcasting, Internet and Telecommunication, Vol. 12 No 2, 77 - 83, 2012</li> <li>• “Simulation of Vacuum Characteristics in Semiconductor Processing Vacuum System by the Combination of Vacuum Pumps”, Hyung-Taek Kim, Dae-Yeon Kim, Journal of the Korean Institute of Electrical and Electronic Material Engineers, Vol 24 No 6, 449 - 456, 2011</li> </ul>
Current Research	<ul style="list-style-type: none"> <li>• Compound semiconductors for optoelectronics : materialization as thin film</li> <li>• Simulation of vacuum system characteristics</li> </ul>